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LABEL NO.

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2598/1G196US1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Sang Kyeong YUN and Dong Hoon KIM

Filed: CONCURRENTLY

SIGNATURE

NAME (PRINT)

For: PIEZOELECTRIC/ELECTROSTRICTIVE FILM ELEMENT FORMED AT LOW

TEMPERATURE USING ELECTROPHORETIC DEPOSITION

PRELIMINARY AMENDMENT

Hon. Commissioner of Patents and Trademarks Washington, DC 20231

Sir:

Prior to examining the above-identified patent application, please enter the following amendment(s):

In the Claims:

Please amend Claims 22 and 41 to read as follows:

22. (Amended) The piezoelectric/electrostrictive film element in Claim 21, wherein the method further comprises a step of drying said piezoelectric/electrostrictive film between g) and h).

41. (Amended) The piezoelectric/electrostrictive film element in Claim 40, wherein the method further comprises a step of drying the piezoelectric/electrostrictive film between g) and h).

Please add the following new claims:

Please add Claims 58-61

- 58. The piezoelectric/electrostrictive film element in Claim 20, wherein the method further comprises a step of drying said piezoelectric/--electrostrictive film between g) and h).
- 59. The piezoelectric/electrostrictive film element in Claim 61, wherein said piezoelectric/electrostrictive film is dried at 70-100°C.
- 60. The piezoelectric/electrostrictive film element in Claim 39, wherein the method further comprises a step of drying the piezoelectric/-electrostrictive film between g) and h).
- 61. The piezoelectric/electrostrictive film element in Claim 63, wherein said piezoelectric/electrostrictive film is dried at 70-100°C.

REMARKS

This patent application includes Claims 1-61 New claims have been added to restore some of the dependencies eliminated by deleting multiple dependencies.

Respectfully submitted,

Joseph B. Lerch Reg. No. 26,936

Attorney for Applicant(s)

DARBY & DARBY P.C. 805 Third Avenue, 27th Flr. New York, NY 10022 212-527-7700